

# INFORMATION REPORT

CD NO.

COUNTRY East Germany

DATE DISTR. 1 December 1952

SUBJECT New Type Optometers Developed at Zeiss Jena

NO. OF PAGES 1

25X1

PLACE  
ACQUIRED

NO. OF ENCLS. 2 (Photographs)  
(LISTED BELOW)

DATE OF  
INFO.

SUPPLEMENT TO  
25X1 REPORT NO.

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1. Carl Zeiss, Jena, has developed two new types of optometers that are to be produced and sold during 1953. They have been developed in the department for technical measurement instruments. The Zeiss terminology for the devices is:
  - a) Projektionsoptometer 1 mu mit senkrechtem Ständer (with vertical stand)
  - b) Projektionsoptometer 0.2 mu mit senkrechtem Ständer.
2. The following data are given for the optometers:
  - a) Scale value..... 1 micron  
Scale part (on screen)..... 1.6 millimeters  
Indication area..... plus or minus 100 microns  
Application area..... 180 millimeters  
Lifting (Freihub)..... 3 millimeters  
Measurement power..... about 120 grams  
Length in the clear (Ausladung)..... 75 millimeters
  - b) Scale value..... 0.2 microns  
Scale part (on screen)..... 1.6 millimeters  
Indication area..... plus or minus 20 microns  
Application area..... 180 millimeters  
Lifting..... 3 millimeters  
Measurement power..... about 120 grams  
Ausladung..... 75 millimeters

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